



Nanoporous Silicon Waveguides for Biosensing Applications

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Overview



- Background lacksquare
- Motivation for research

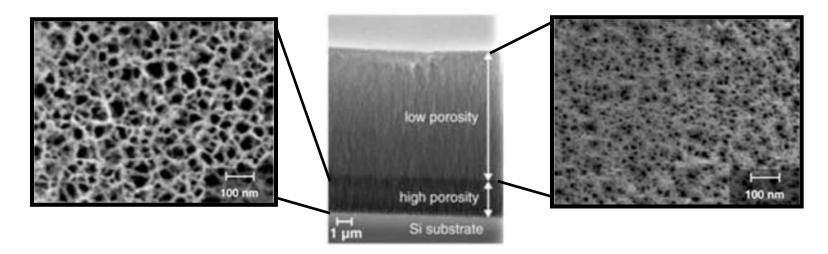
BIEN 2008

- Fabrication process
- Preliminary results
 - Infrared imaging of modes
 - Power transmission and loss
- Summary of accomplishments





- Electrochemical etching of silicon
 - Nanoscale pore size << wavelength of light
 - Multi-layer structure formed by varying applied current density



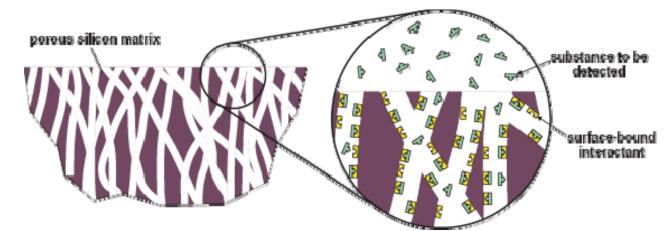
- Advantages of Material
 - Simple fabrication, tunable refractive index ($n_{air} < n_{eff} < n_{Si}$)
 - High surface area to volume ratio \rightarrow better sensitivity



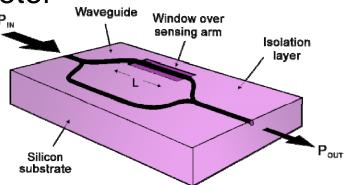
Motivation



- Label-free biodetection
 - Fast, inexpensive, portable applications
 - Optical property changes in the presence of biomolecules



- Our Goal: Mach-Zehnder interferometer
 - Conjugate interactants to surface
 - Measure peak shifts and alterations in material's refractive index

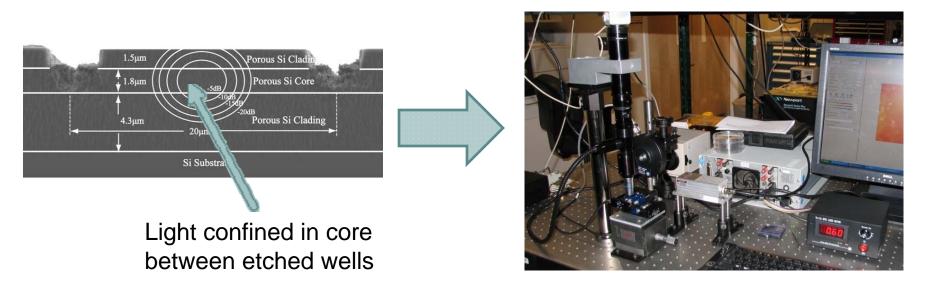




Fabrication



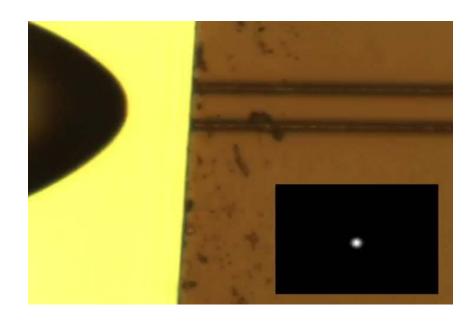
- Laser local oxidation to define guided path
 - Motorized XY stage controls oxidation of wells
 - Real-time imaging of wafer during writing



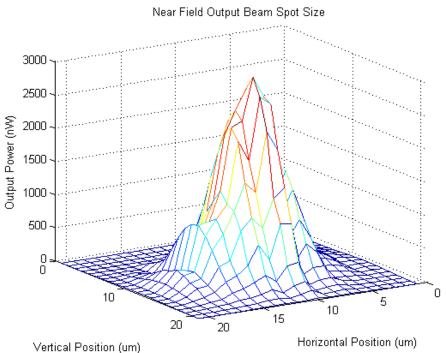
- Power transmission measurements
- Infrared photography of output beam



- Linear waveguide 5 mm long, optimal width 20 μm
 - − P_{in} = 1.4 mW, P_{out} = 8 µW → Total insertion loss = -22 dB
- Single mode beam at output



Light at output changes as input fiber moves across waveguide

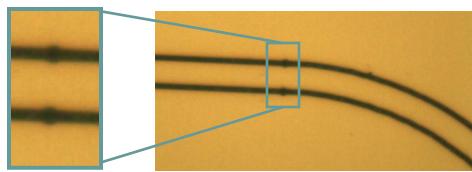


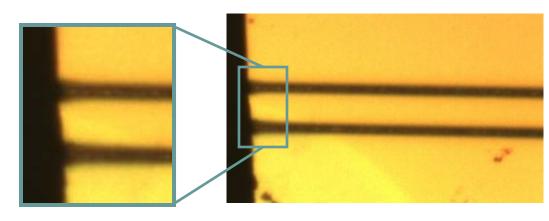


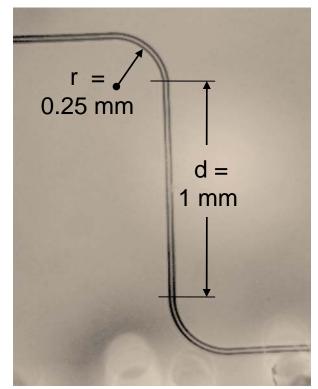
Results



- 90° bend waveguide exhibits high loss
 - Curved path may contribute to light leakage
 - Flaws in oxide at edges and bends
- Next step: Vary radii to determine loss dependency









Summary



- Designed, built and programmed scanning laser system for defining guided paths
- Successfully fabricated single-mode porous Si waveguides and measured insertion loss
- Future research
 - Determine optimal parameters to reduce bending and scattering loss
 - Fabricate Mach-Zehnder interferometer

Any Questions?